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INFORMATION DISCLOSURE STATEMENT

BY APPLICANT

Docket: 6047-53072

App: 09/590,791^{PTO}

Applicant: Cem Basceri et al.

Filed: June 8, 2000

Art Unit: 2822

U.S. PATENT DOCUMENTS

Init.*	Number	Date	Name	Class	Sub	Filed
TMT	6,060,367	5/9/00	Sze	438	398	
	6,060,351	5/9/00	Parekh et al.	438	253	
	6,049,101	4/11/00	Graettinger et al.	257	296	
	6,037,220	3/14/00	Chien et al.	438	255	
	6,015,743	1/18/00	Zahurak et al.	438	398	
	5,962,065	10/5/99	Weimer et al.	427	8	
	5,985,714	11/16/99	Sandhu et al.	438	253	
	5,959,327	9/28/99	Sandhu et al.	257	310	
	5,877,063	3/2/99	Gilchrist	438	398	
	5,696,014	12/9/97	Figura	438	398	
	5,612,560	3/18/97	Chivukula et al.	257	309	
	5,608,247	3/4/97	Brown	257	306	
	5,427,974	6/27/95	Lur et al.	438	396	
	5,372,962	12/13/94	Hirota et al.	438	398	
	5,342,800	8/30/94	Jun	438	396	
TMT	5,318,920	6/7/94	Hayashide	438	398	

EXAMINER: T. M. Thomas

DATE 11-25-02

*Examiner: Initial if considered, whether or not in conformance with MPEP 60;
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Init.*		Number	Date	Name	Class	Sub	Filed
TMT		5,130,885	7/14/92	Fazan et al.	361	313	
1		5,068,199	11/26/91	Sandhu	438	255	
FOREIGN PATENT DOCUMENTS							
		Number	Date	Country	Class	Sub	
OTHER DOCUMENTS							
TMT			Kawahara, Takaaki et al., "(Ba, Sr)TiO ₃ Films Prepared by Liquid Source Chemical Vapor Deposition on Ru Electrodes," <u>Jpn. J. Appl. Phys.</u> , 35:4880-4885 (1996).				
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